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Applicant: Toru YAMADA, et al.

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For: Vapor Phase Growth Apparatus and Method of Fabricating

Epitaxial Wafer

INFORMATION DISCLOSURE STATEMENT - PTO FORM 1449

U.S. PATENT DOCUMENTS						
Examiner Initials*	U.S. Patent Document Number	Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY			
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Examiner Initials*	Foreign Patent Document Number	Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	T**			
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Examiner Signature	/Felisa Hiteshew/	Date Considered	09/09/2008

^{*}Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

^{**}Applicant is to place a check mark here if English language translation is attached